



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	PATENT APPLICATION
Inventors:	Jong-Jan Lee and Sheng Teng)
	Hsu)
Serial No.:	10/625,065)
Filed:	July 22, 2003)
Title:	FABRICATION OF SILICON-ON- NOTHING (SON) MOSFET)
	FABRICATION USING)
	SELECTIVE ETCHING OF)
	Si _{1-x} Ge _x LAYER)
)

CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8

I hereby certify that this correspondence is being deposited
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Victoria A. Woods
Signature Date : January 14, 2004

STATUS INQUIRY

Hon. Commissioner for Patents
Alexandria, VA 22313-1450

Sir:

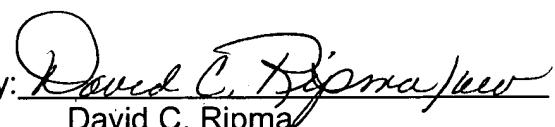
Applicants have not received a filing receipt for the above-identified application.
Accordingly, applicants' attorney-of-record, whose name and address appear below,
hereby inquires as to the status of the above-identified application.

Please direct all correspondence in this application to the following:

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Respectfully submitted,

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